

Electronic Acknowledgement Receipt

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EFS ID:	1193633
Application Number:	10598933
Confirmation Number:	2213
Title of Invention:	Semiconductor wafer inspection device and method
First Named Inventor:	Fumi Nabeshima
Customer Number:	44719
Filer:	Joseph Patrick Farrar
Filer Authorized By:	
Attorney Docket Number:	PA214WP002
Receipt Date:	14-SEP-2006
Filing Date:	
Time Stamp:	21:19:36
Application Type:	U.S. National Stage under 35 USC 371
International Application Number:	PCT/JP05/12345

Payment information:

Submitted with Payment	yes
Payment was successfully received in RAM	\$900
RAM confirmation Number	753
Deposit Account	503546

File Listing:

Document Number	Document Description	File Name	File Size(Bytes)	Multi Part	Pages

1	Drawings	fig01-fig06.pdf	494922	no	6			
Warnings:								
Information:								
2	Application Data Sheet	ADSKomatsuElec.pdf	412012	no	4			
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3	Assignee showing of ownership per 37 CFR 3.73(b).	US_Assignment.pdf	72337	no	1			
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5	Transmittal letter	NewUtilityPatentApplication. pdf	41043	no	2			
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6		PKM050074PCT_SPEC.pdf	5050056	yes	39			
	Multipart Description							
	Doc Desc			Start	End			
	Specification			1	34			
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	Abstract			39	39			
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Electronic Patent Application Fee Transmittal

Application Number:				
Filing Date:				
Adjustment date: 01/18/2008 SDIRETA1 09/15/2006 INTEFSW 00000753 503546 10598933 01 FC:1631 300.00 CR 02 FC:1642 400.00 CR 03 FC:1633 200.00 CR				
8/2008 SDIRETH1 00000001 503546 10598933 C:1011 300.00 DA C:1111 500.00 DA C:1311 200.00 DA	Semiconductor wafer inspection device and method			
First Named Inventor:	Fumi Nabeshima			
Filer:	Joseph Patrick Farrar			
Attorney Docket Number:	PA214WP002			
Filed as Large Entity				
U.S. National Stage under 35 USC 371 Filing Fees				
Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Basic Filing:				
National Stage Fee	1631	1	300	300
Natl Stage Search Fee - Report provided	1642	1	400	400
National Stage Exam - all other cases	1633	1	200	200
Pages:				
Claims:				
Miscellaneous-Filing:				
Petition:				
Patent-Appeals-and-Interference:				

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